

FIG. 1A  
PRIOR ART

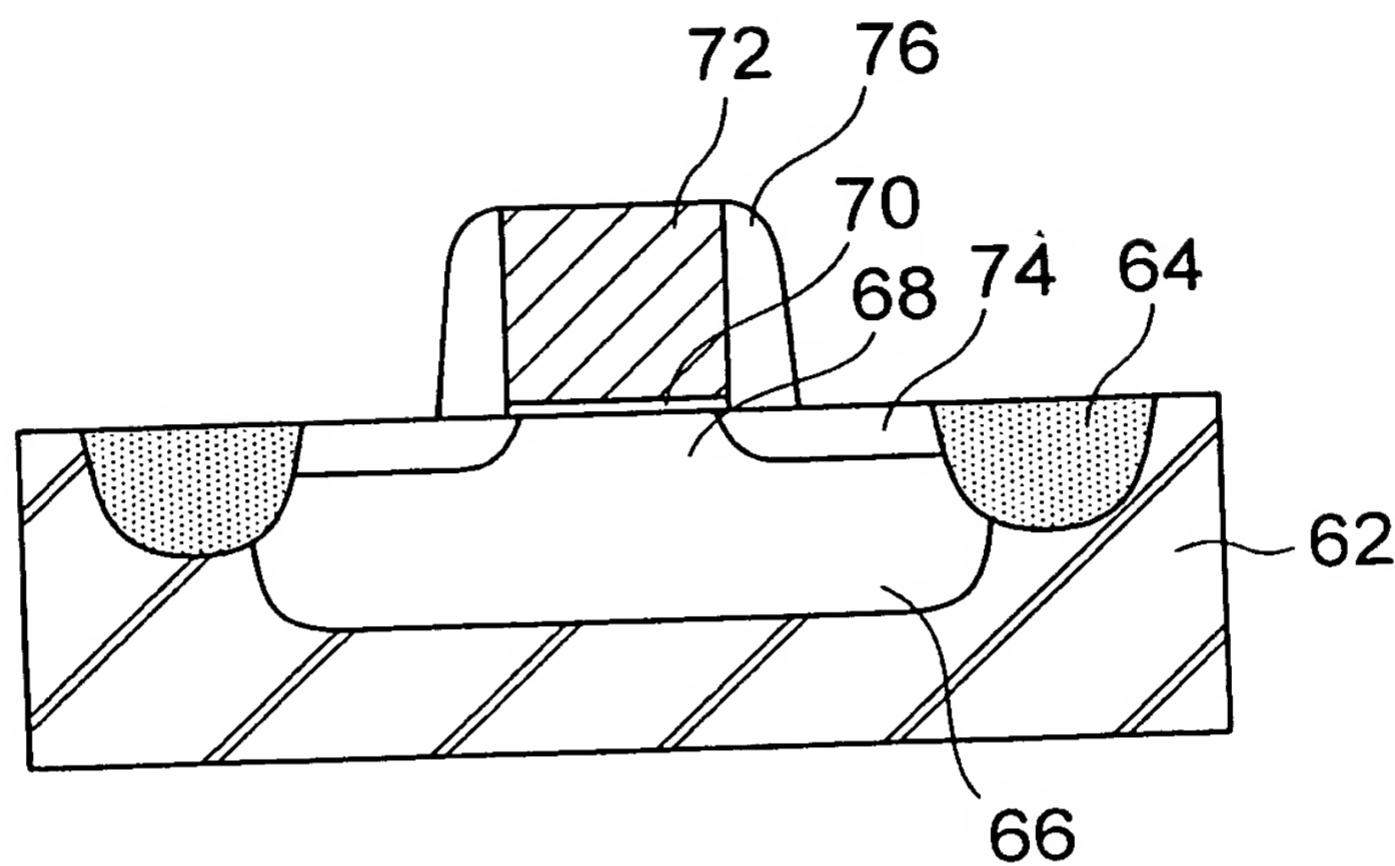


FIG. 1B  
PRIOR ART

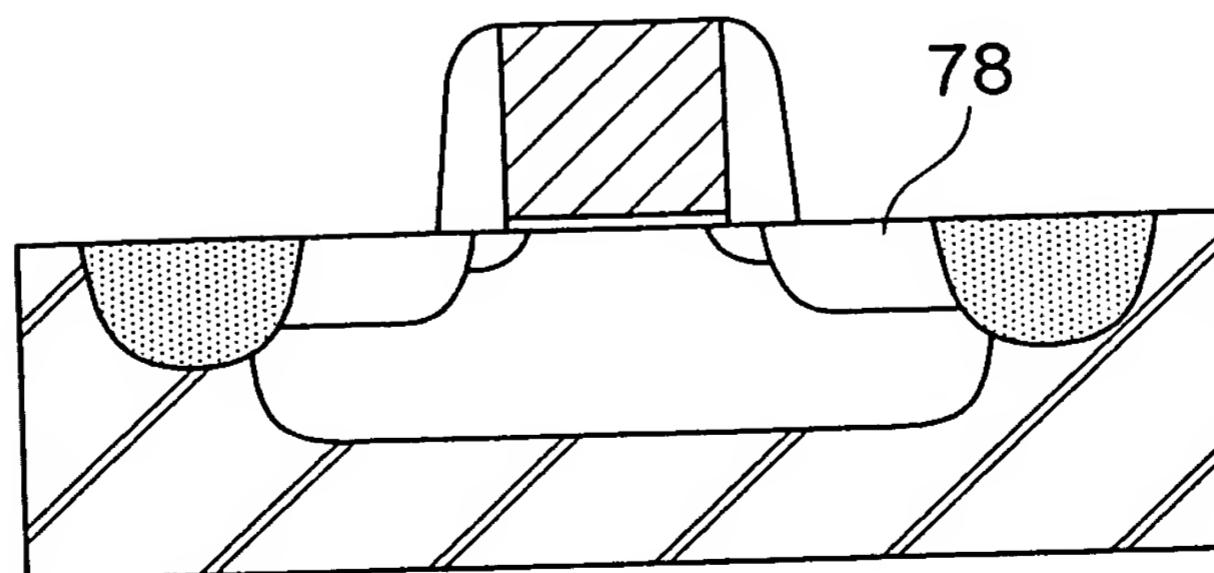


FIG. 2

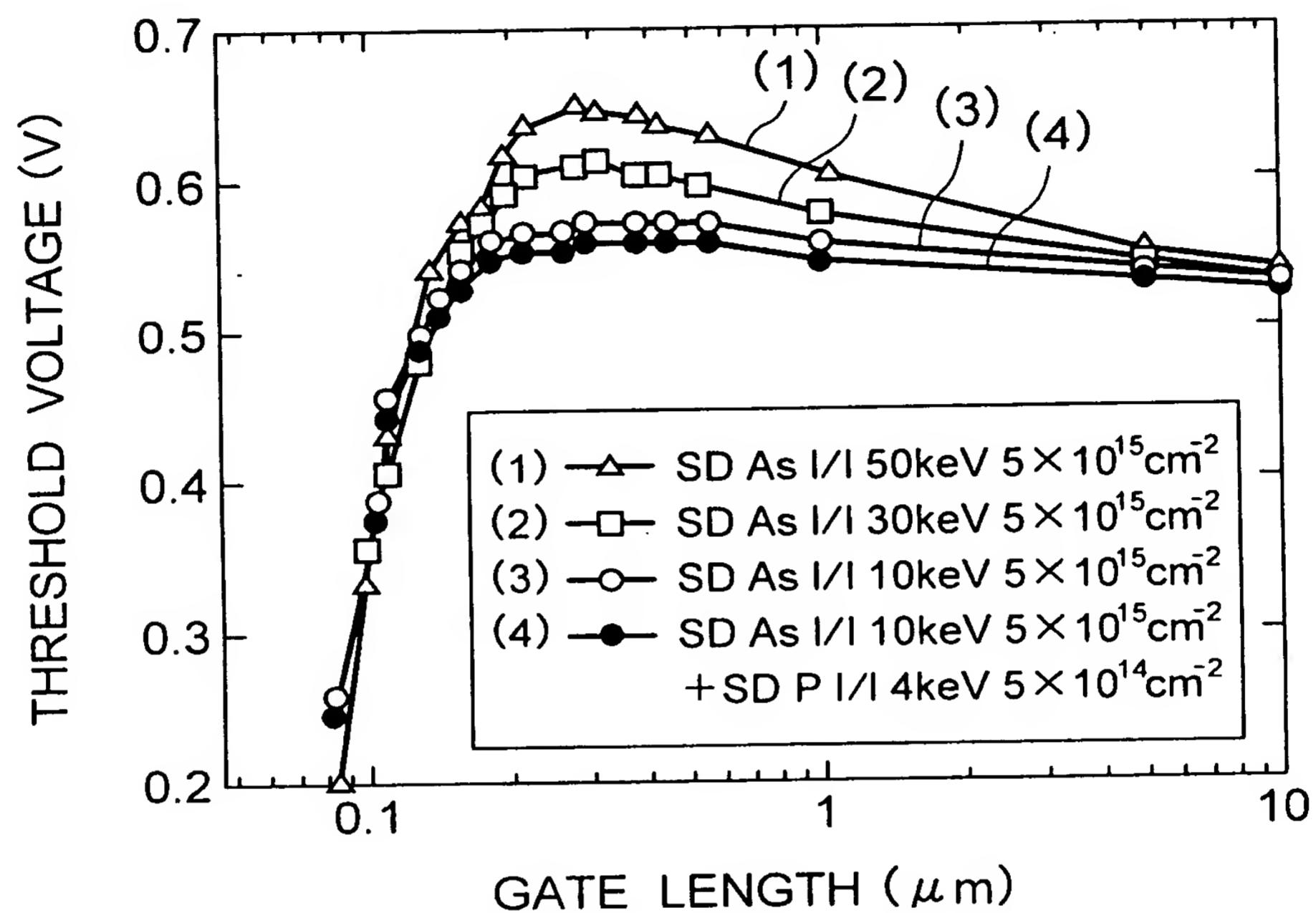


FIG. 3

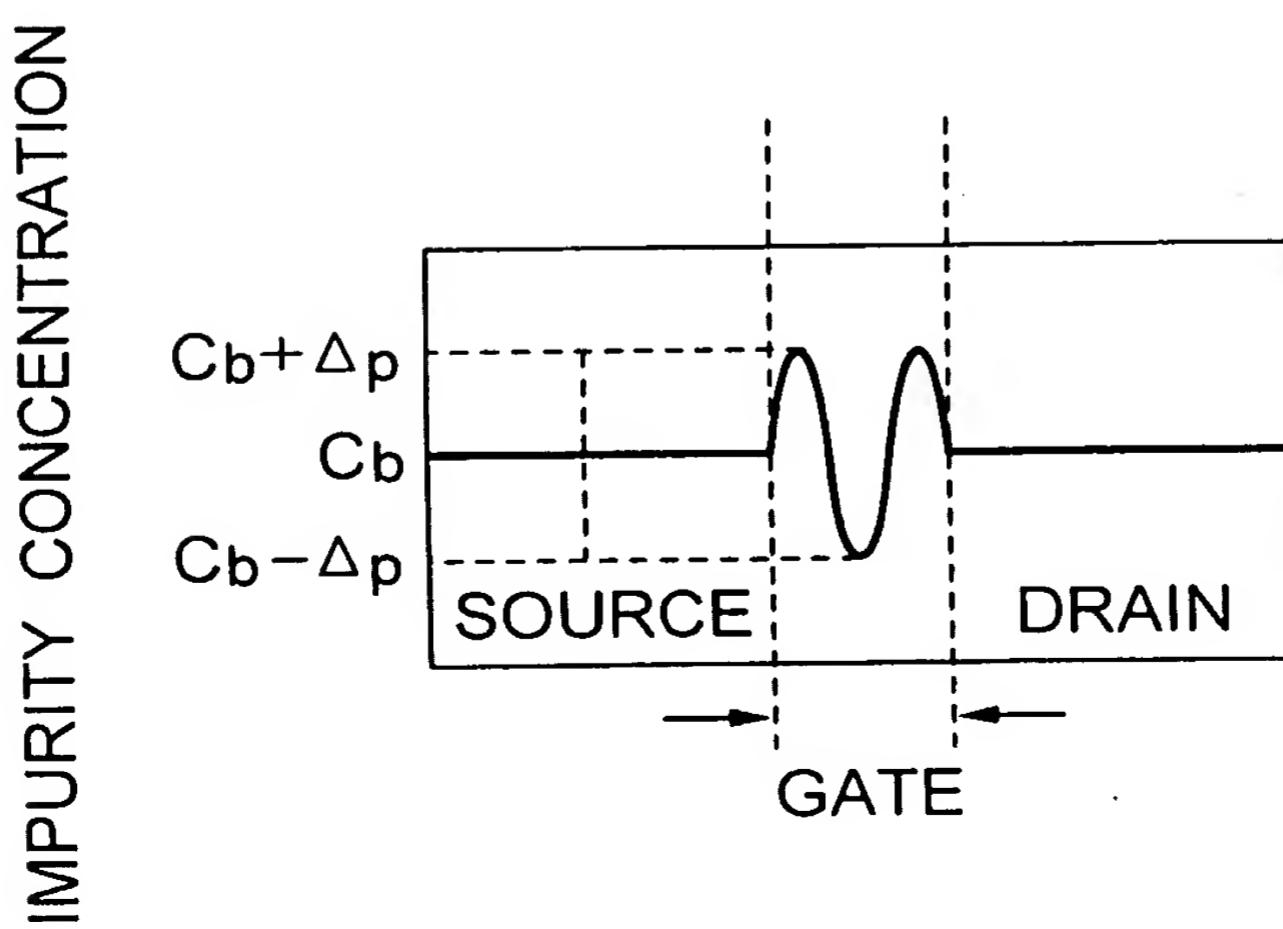


FIG. 4

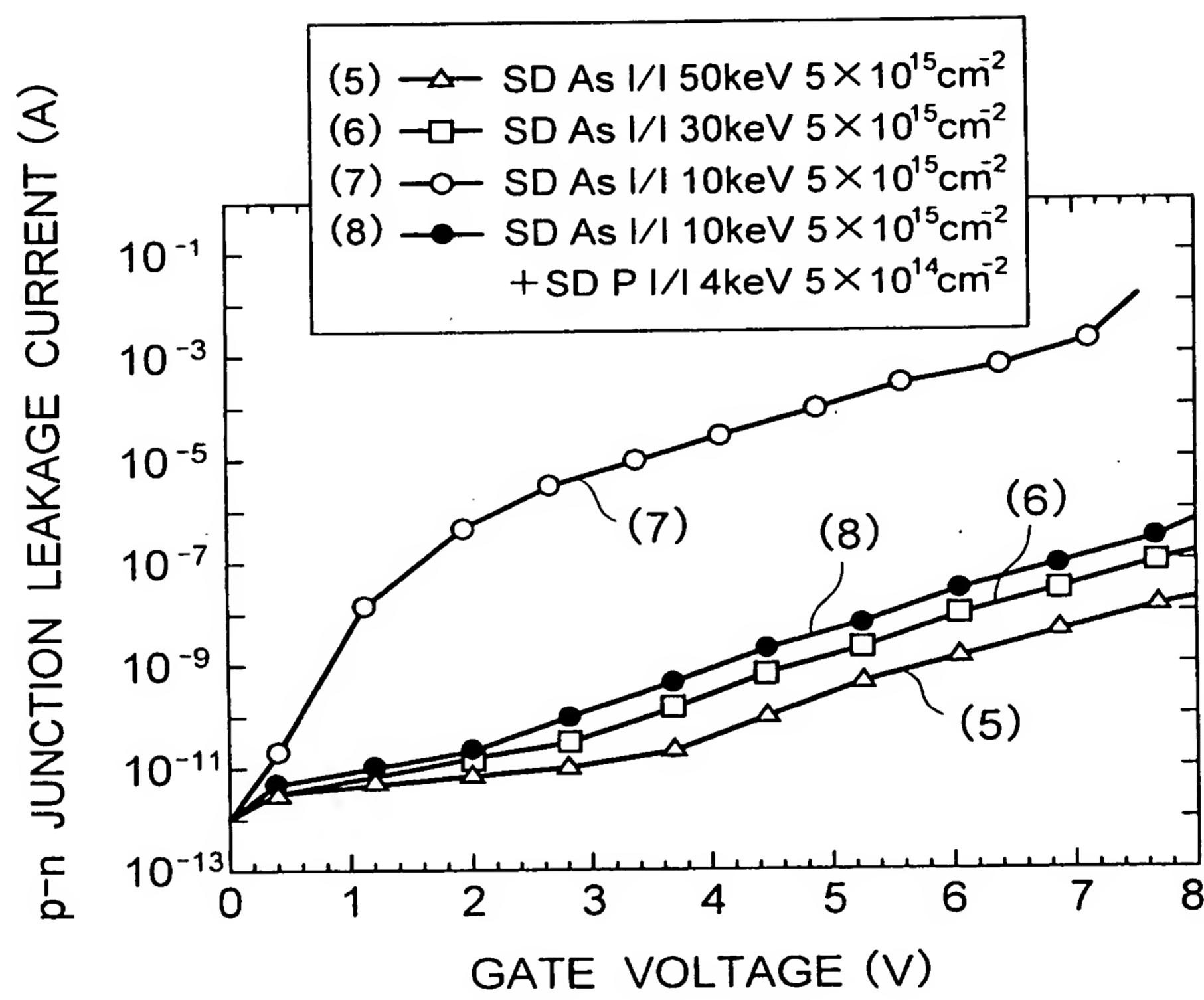


FIG. 5

INTERFACE BETWEEN AMORPHOUS SILICON  
REGION AND SILICON MONOCRYSTALLINE  
REGION WHEN As IS IMPLANTED AT  
 $10\text{keV}$  AND  $5 \times 10^{15}\text{cm}^{-2}$

INTERFACE BETWEEN AMORPHOUS SILICON  
REGION AND SILICON MONOCRYSTALLINE  
REGION WHEN As IS IMPLANTED AT  
 $50\text{keV}$  AND  $5 \times 10^{15}\text{cm}^{-2}$

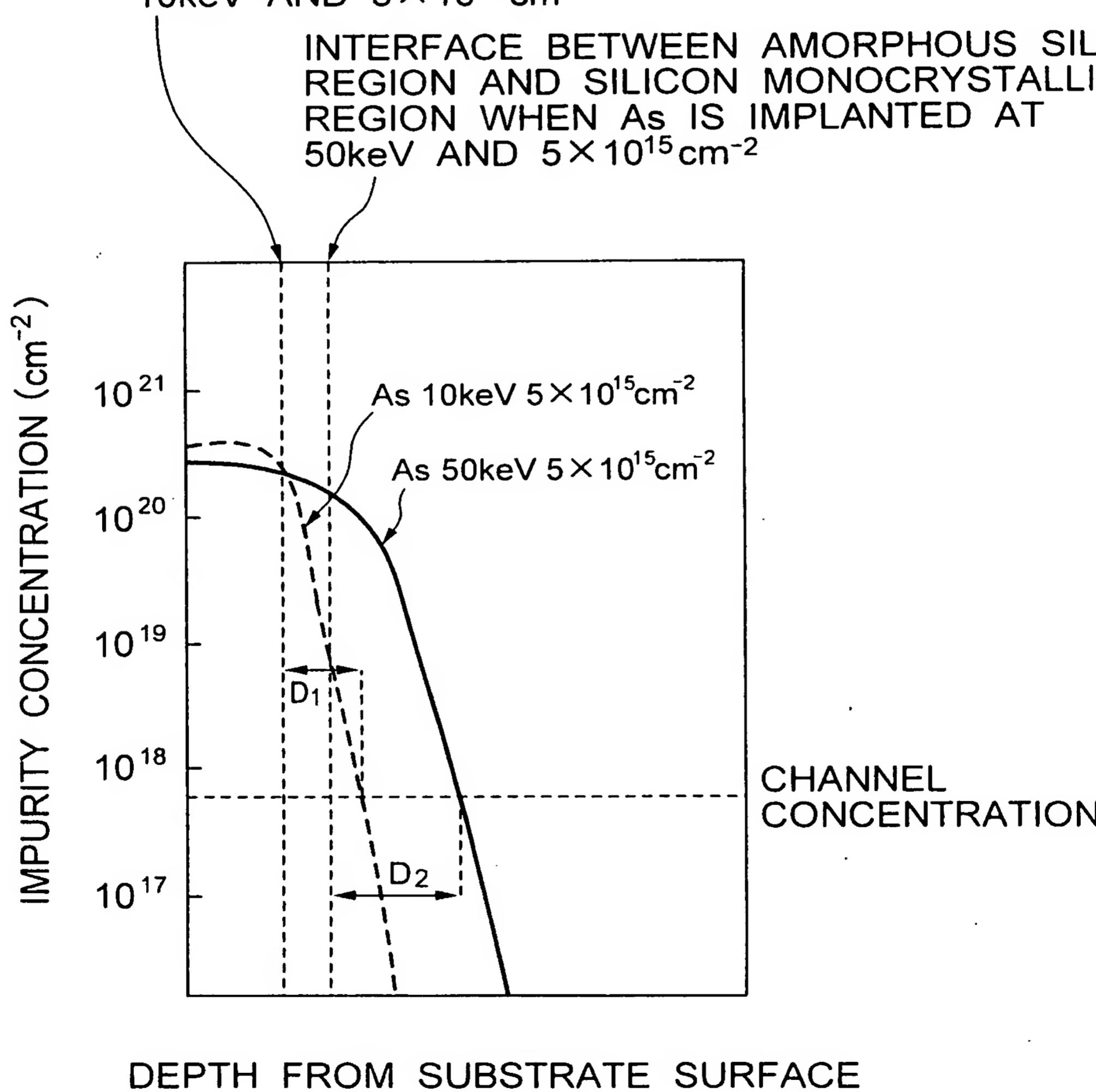


FIG. 6

INTERFACE BETWEEN AMORPHOUS SILICON REGION  
AND SILICON MONOCRYSTALLINE REGION

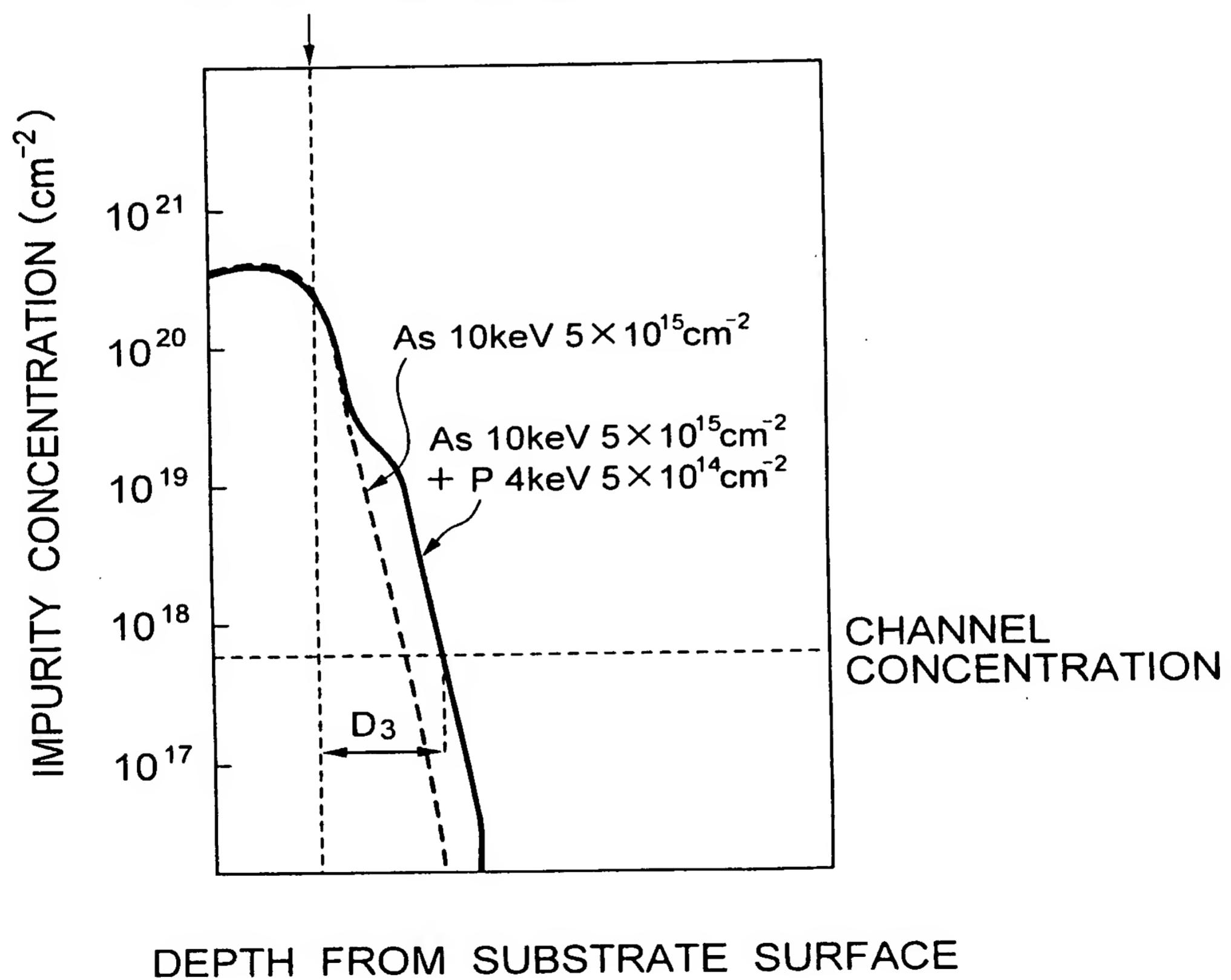


FIG. 7

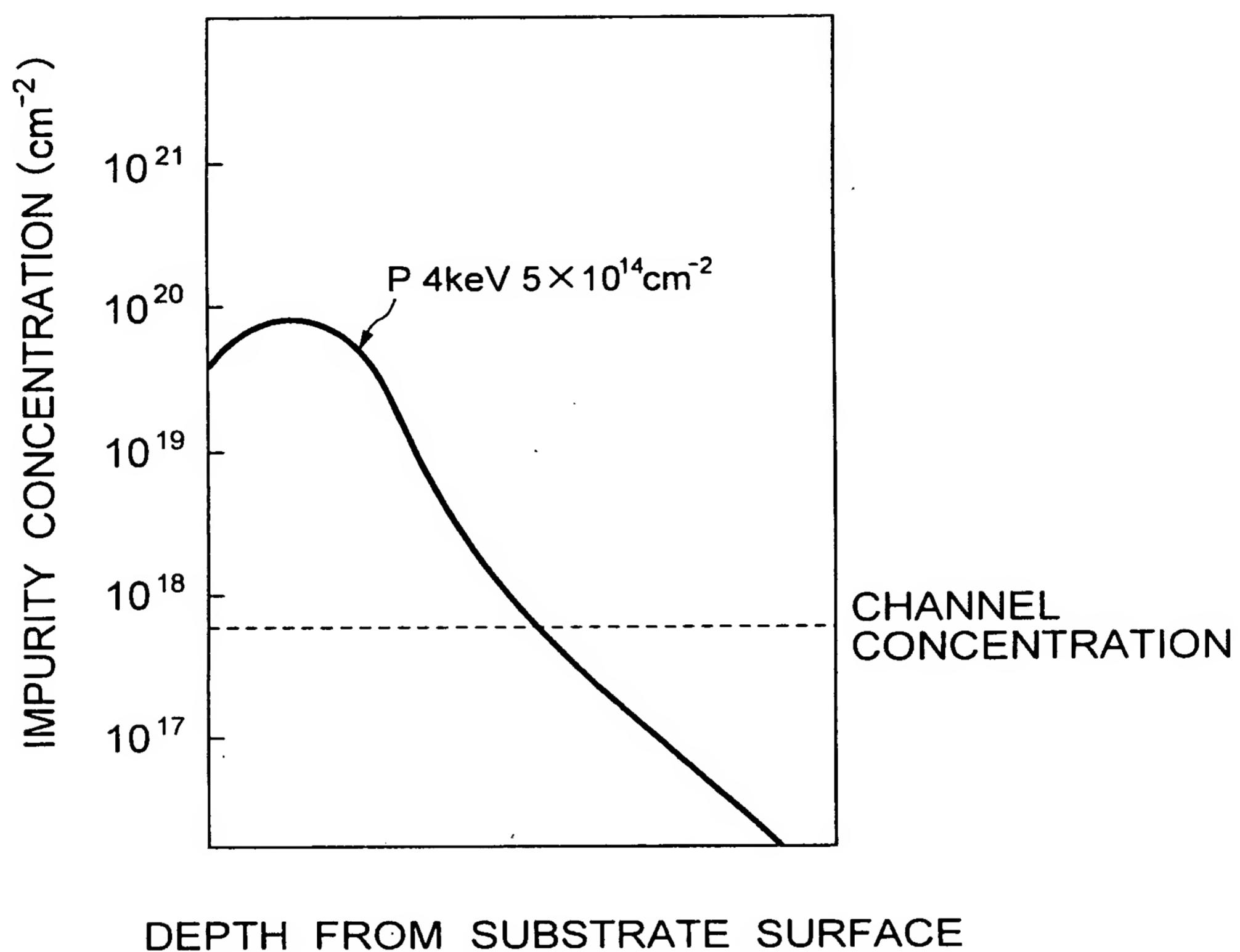


FIG. 8

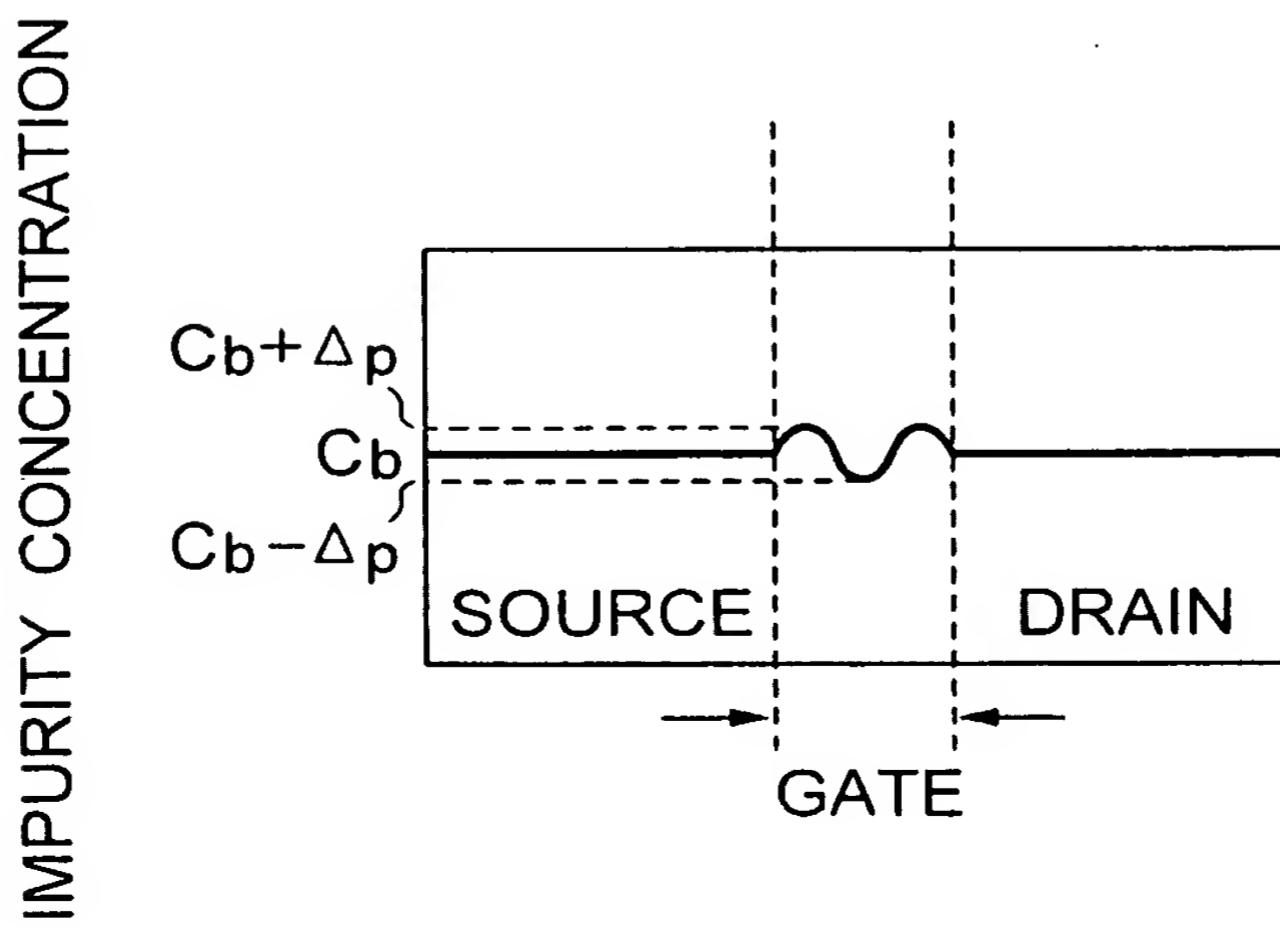
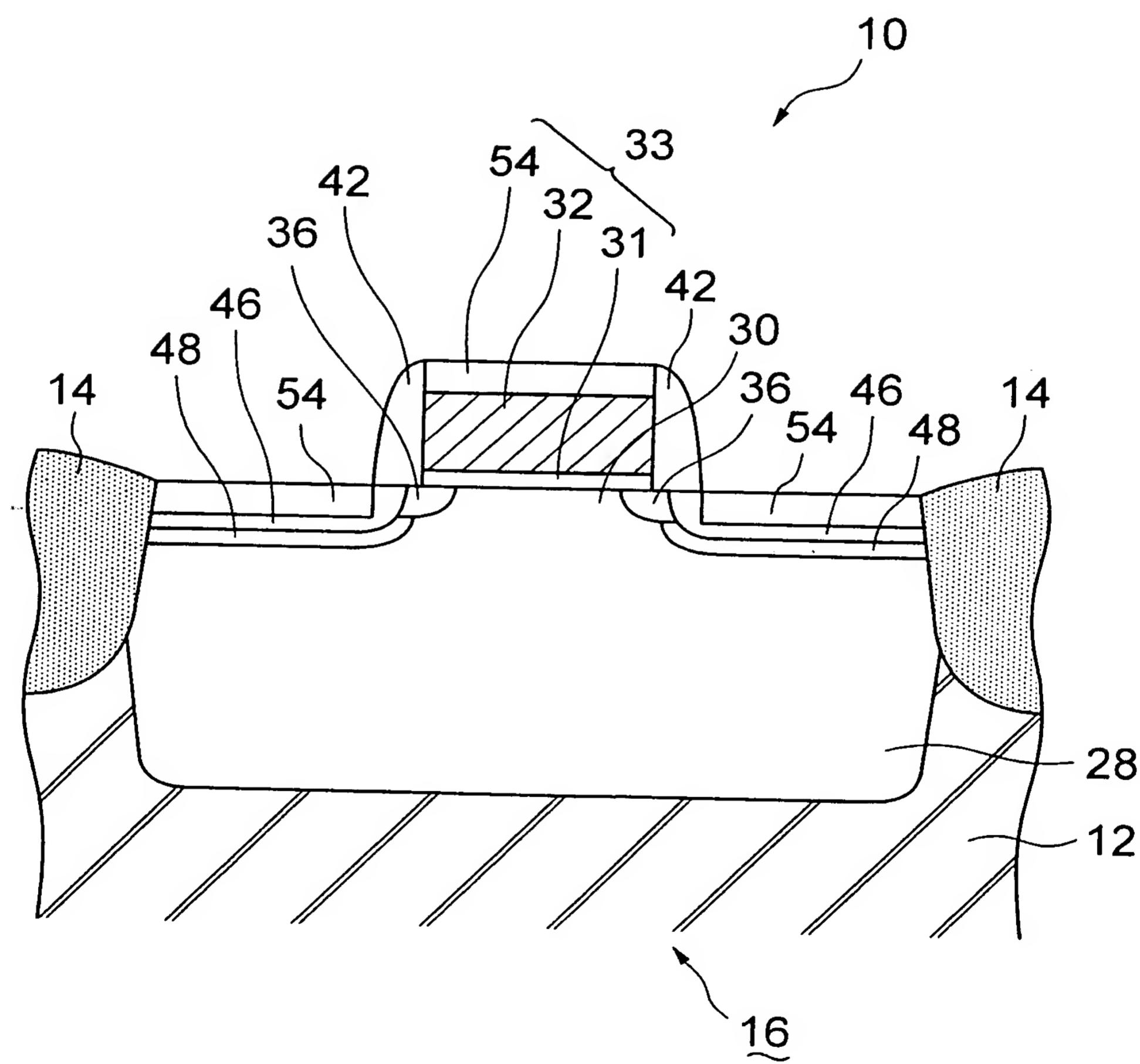
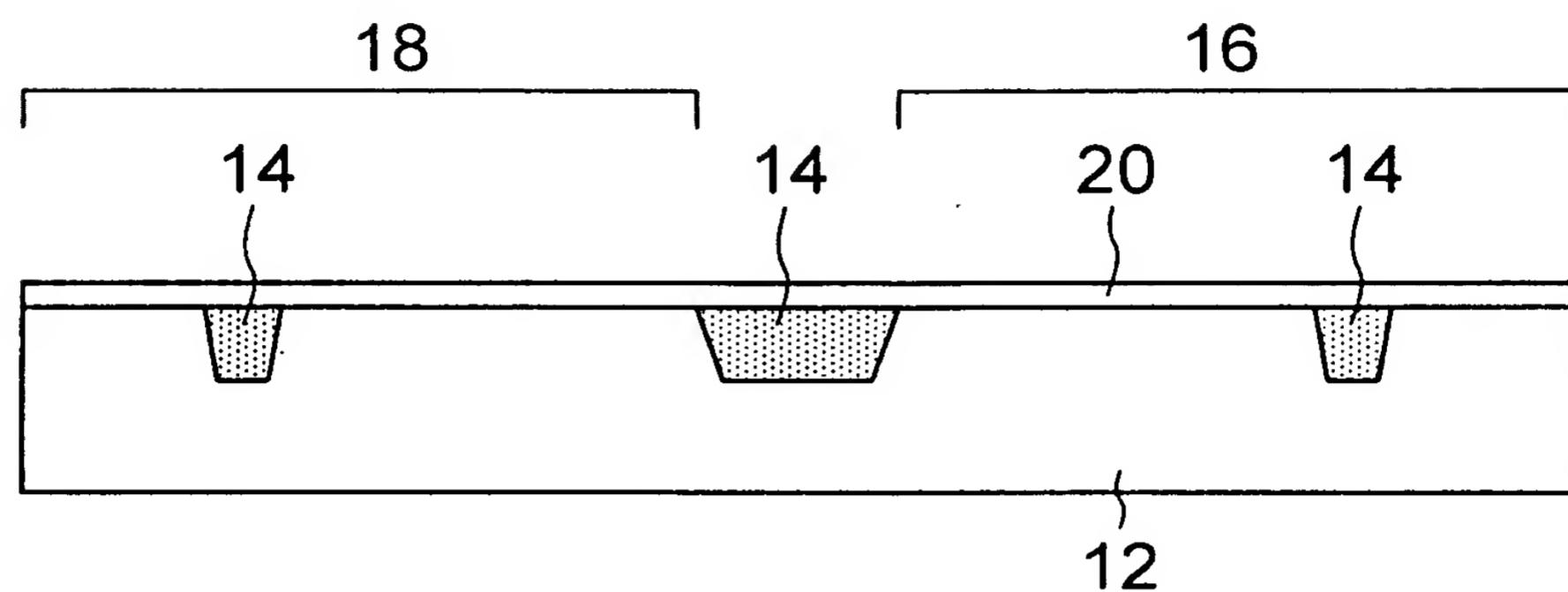


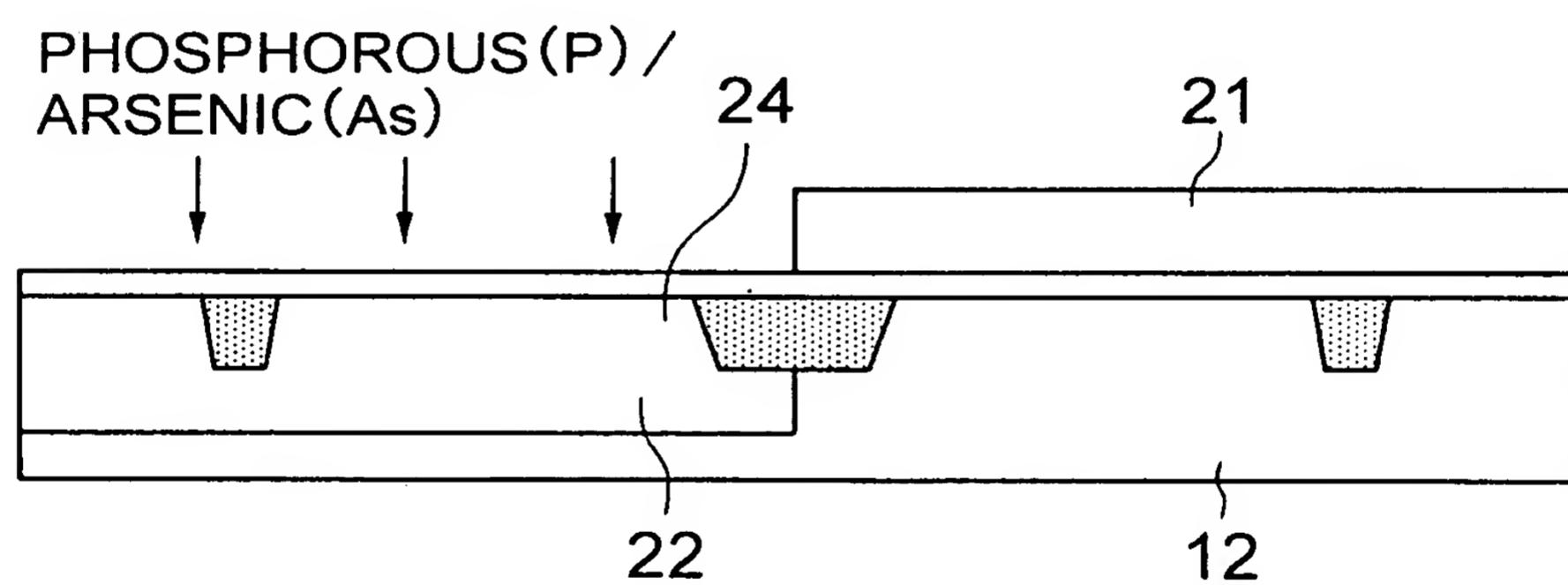
FIG.9



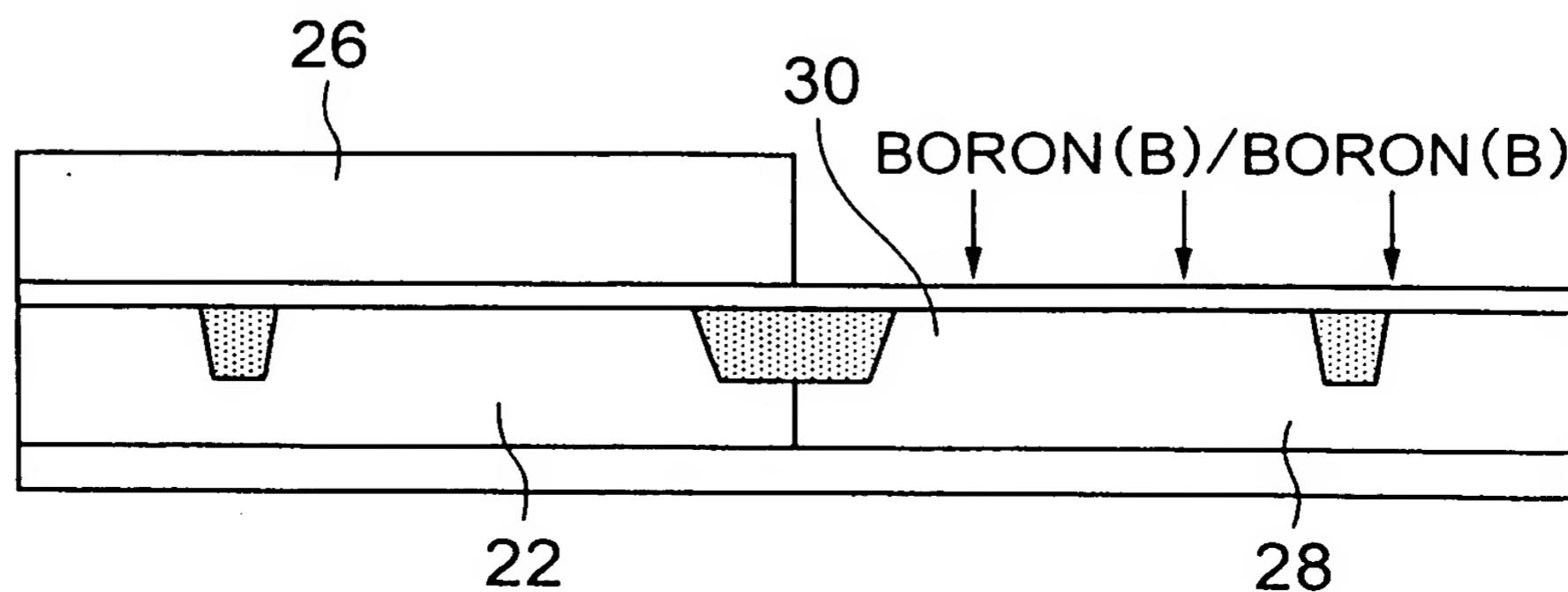
## FIG.10A



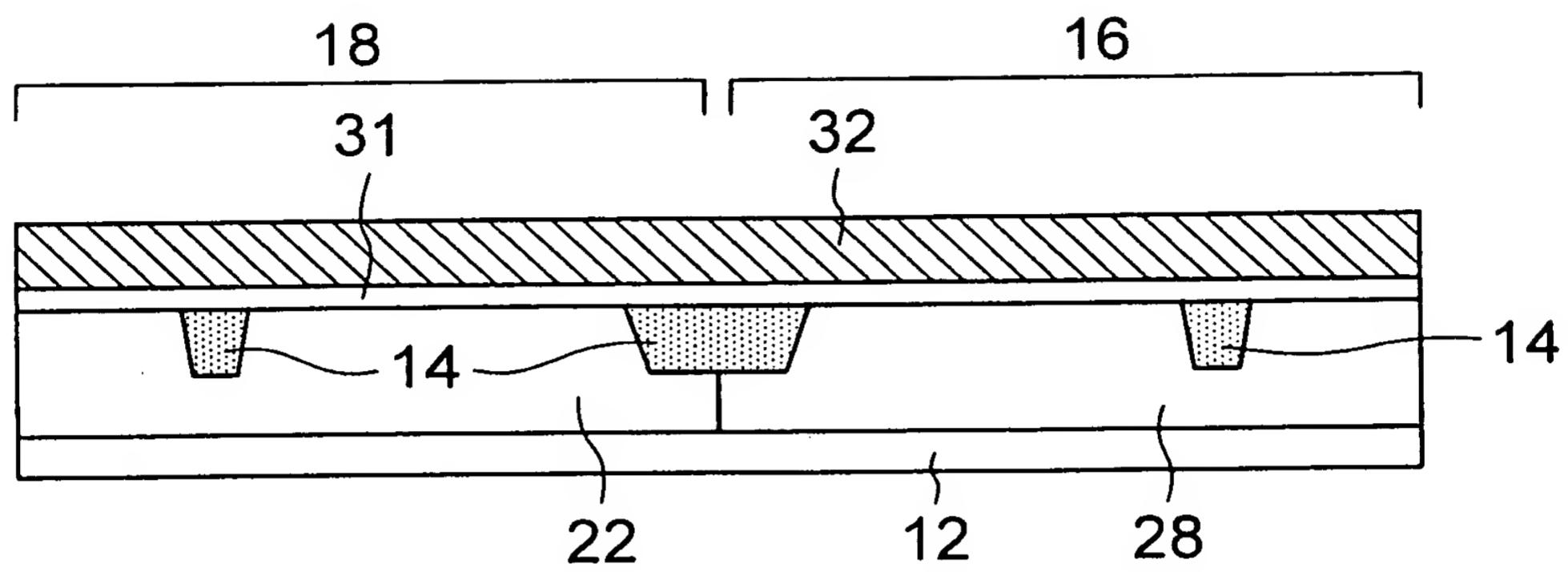
## FIG.10B



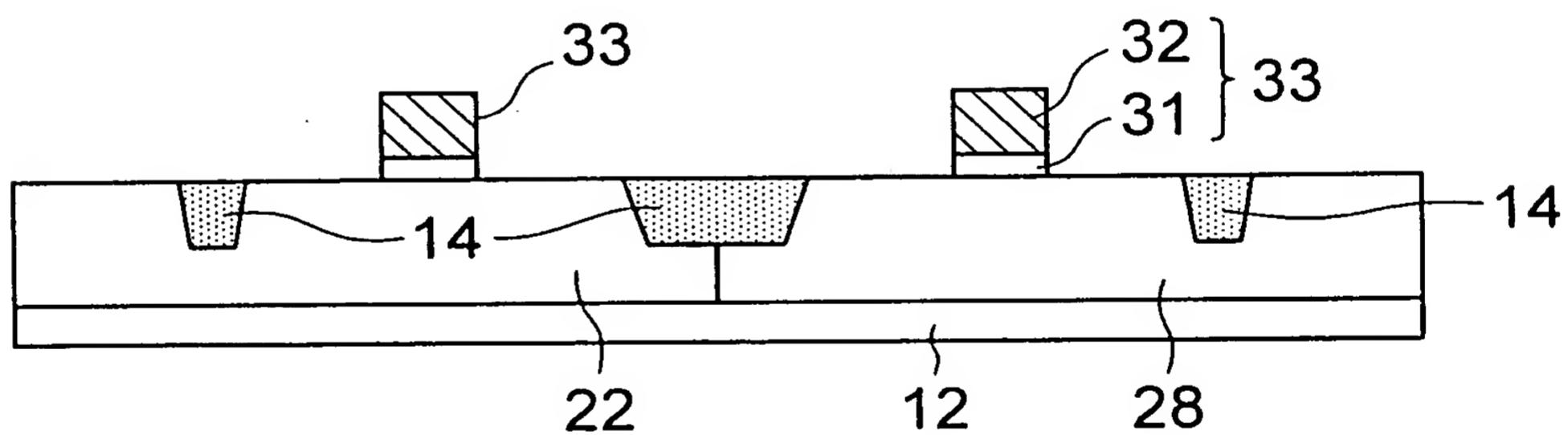
## FIG.10C



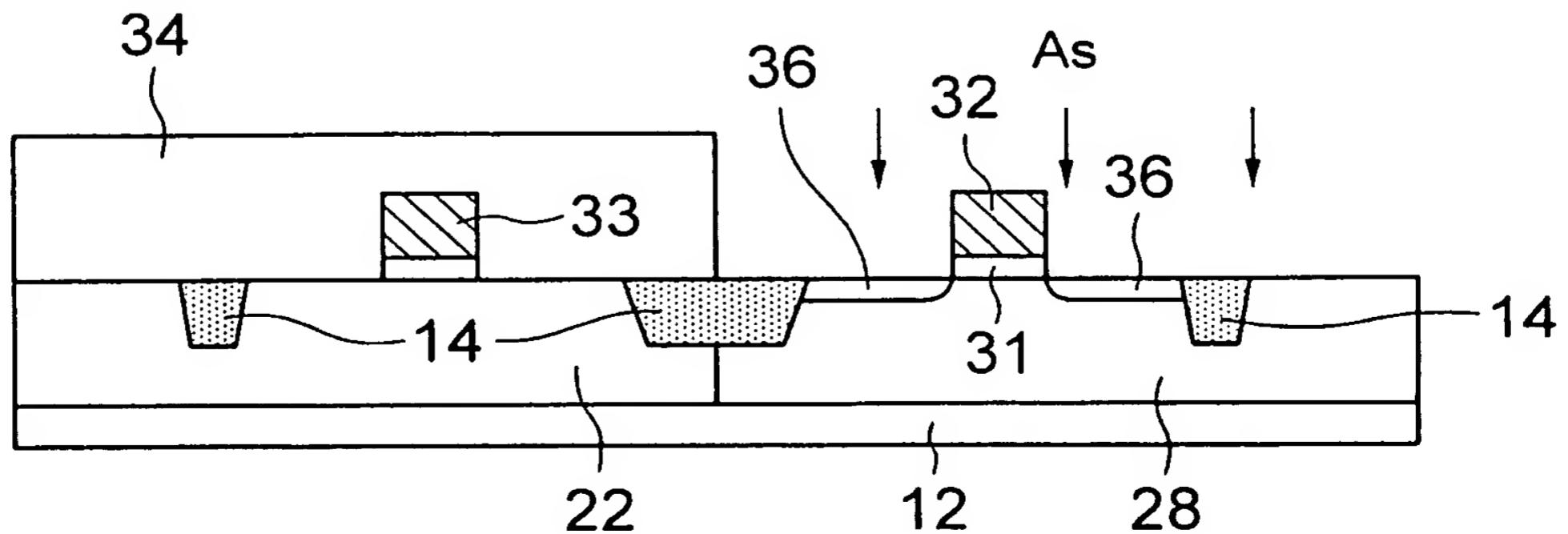
**FIG.10D**



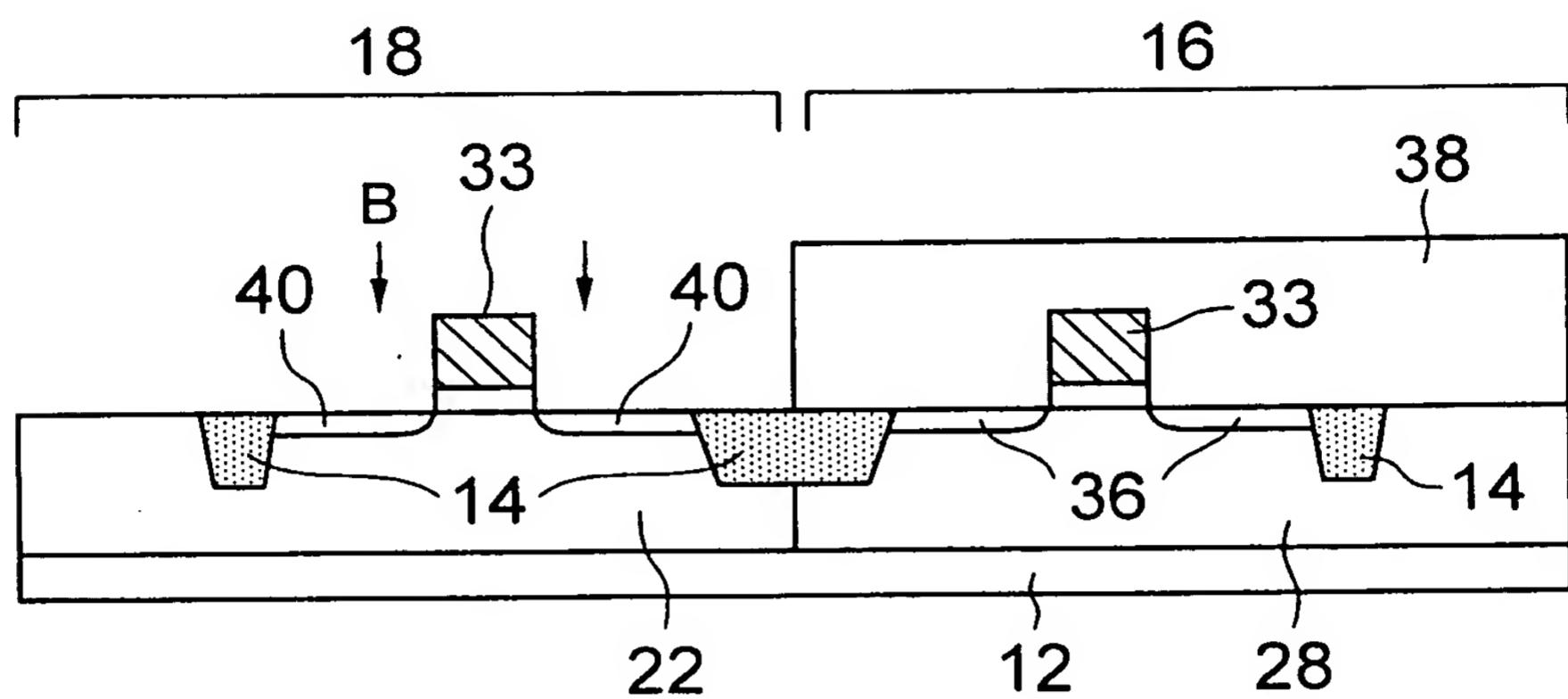
**FIG.10E**



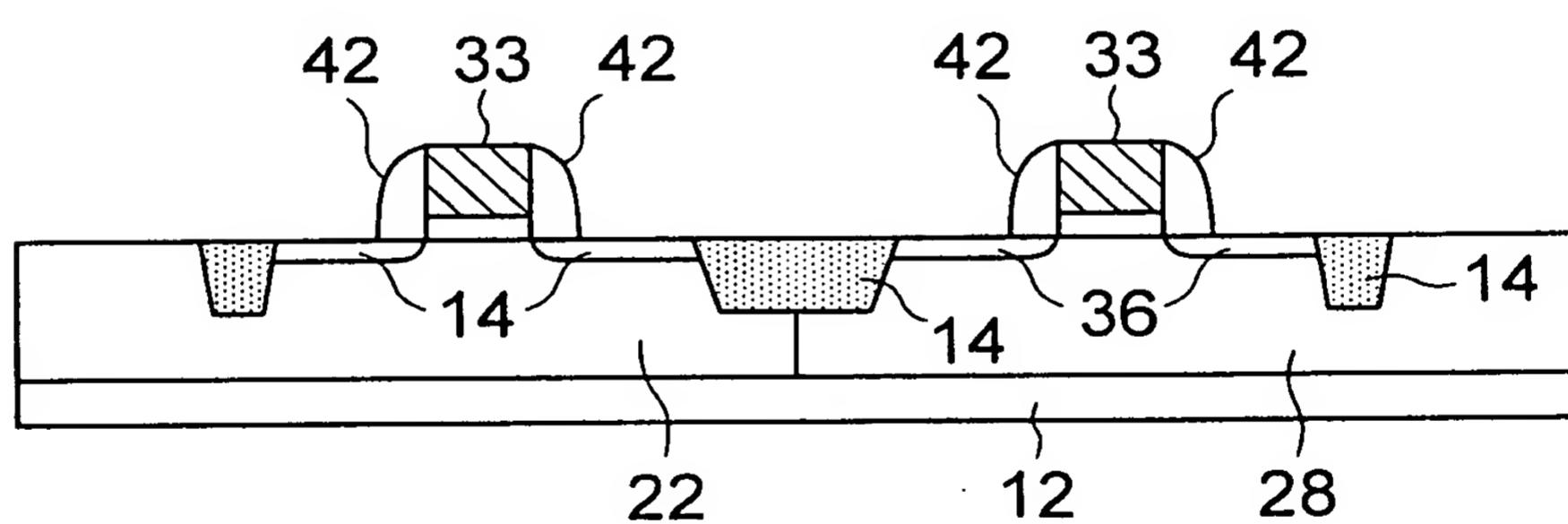
**FIG.10F**



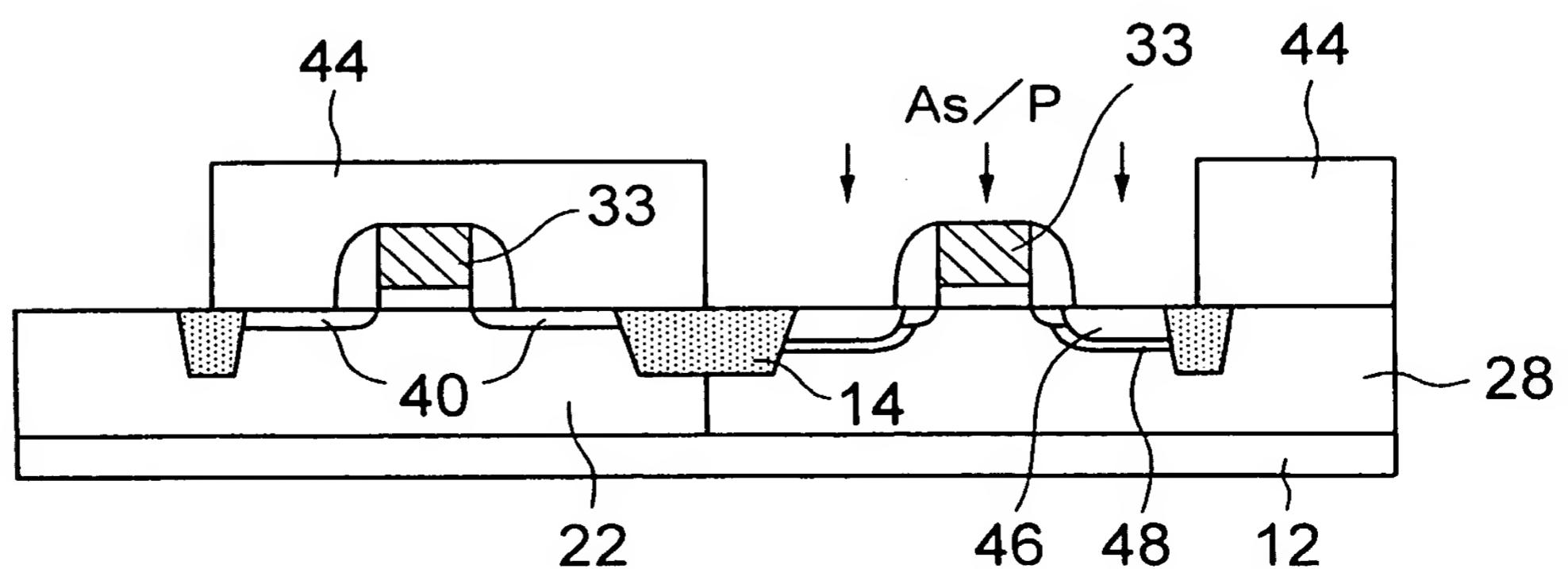
**FIG. 10G**



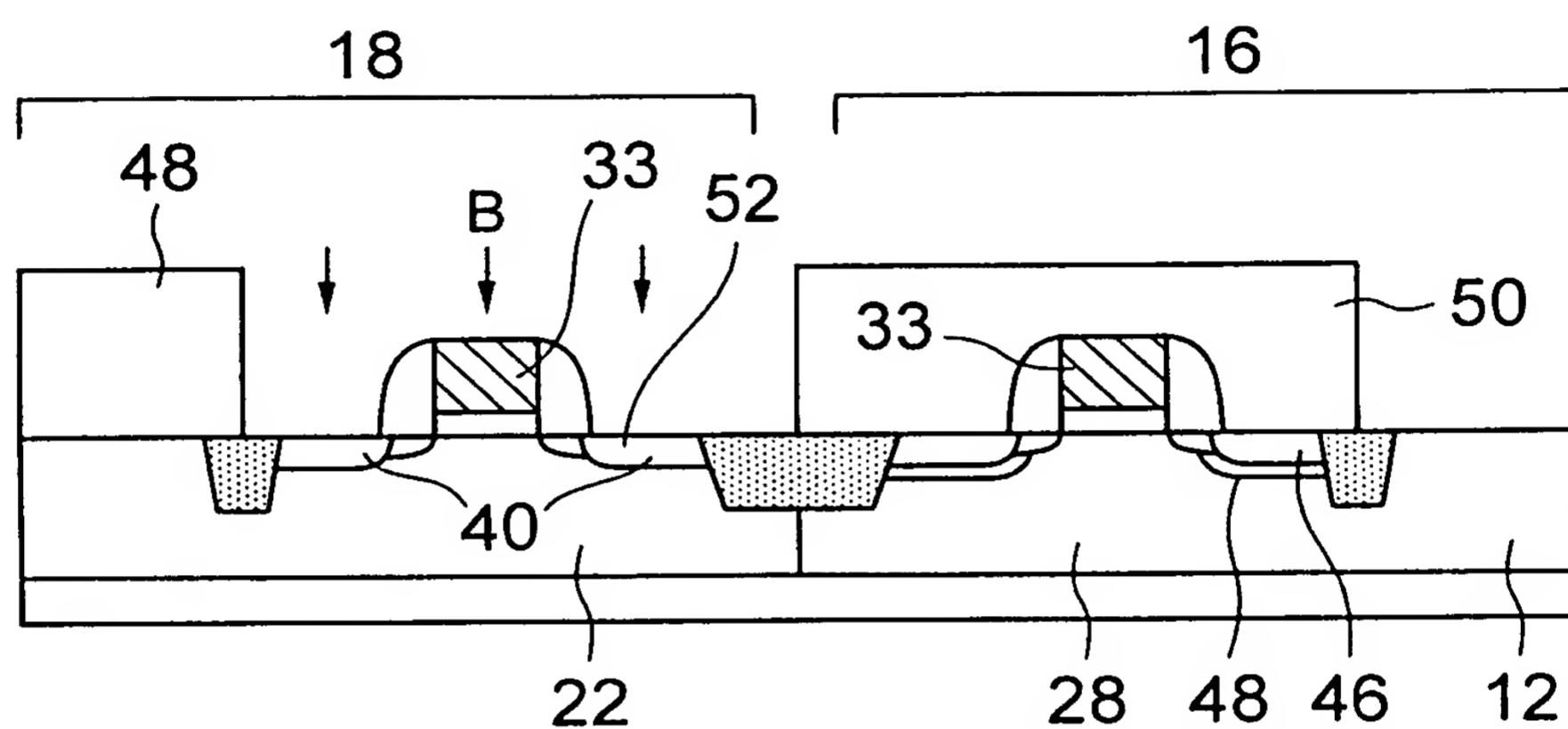
**FIG. 10H**



**FIG. 10 I**



**FIG.10J**



**FIG.10K**

